

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	••	:	Examiner: Unassigned
Kazunori IWAMOTO, et al.)	
		:	Group Art Unit: 2812
Appln. No.: 09/866,600)	
• •		:	
Filed: May 30, 2001)	
	·	:	
For:	STAGE APPARATUS WHICH)	September 27, 2001
	SUPPORTS INTERFEROMETER,	:	
	STAGE POSITION MEASUREMENT)	
	METHOD, PROJECTION EXPOSURE	:	
	APPARATUS, PROJECTION)	
	EXPOSURE APPARATUS	:	
	MAINTENANCE METHOD,)	
	SEMICONDUCTOR DEVICE	:	
	MANUFACTURING METHOD, AND)	
	SEMICONDUCTOR MANUFACTURIN	IG:	
	FACTORY)	

Commissioner for Patents Washington, D.C. 20231

<u>INFORMATION DISCLOSURE STATEMENT</u>

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents are also enclosed.

FEE STATEMENT

No fee or statement is required in connection with this Information Disclosure statement, since it is being submitted prior to the last of (1) issuance of a first official action on the merits or (2) expiration of the three month period following filing of the above-captioned application.

REMARKS

Applicants request that the cited information be considered by the Examiner and that an annotated copy of the enclosed Form PTO-1449 be returned with the next official communication indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

Attorney for Applicants

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